SHEET 1 OF 1

INFO	CIT	ΑT	ON DISCLOS ION IN AN ICATION	ÜRE	ATTY. DOCKET NO. 050212-0559		SERIAL NO. 10/774,417				
THE DECEMBER OF THE PARTY OF TH					APPLICANT Yosihki NISHIBAYASHI, et al.						
(PTO-1449)					FILING DATE February 10, 20	GROUP 1763					
U.S. PATENT DOCUMENTS											
EXAMINER'S INITIALS	CITE NO.	Nur	Document Number nber-Kind Code2 (# known)	Publication Date MM-DD-YYYY		Name of Patentee or Applicant of Cited Document			Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear		
		US									
<b>//</b>		US					<del> </del>				
		US					<del> </del>				
····	<b></b>	US					<del> </del>				
	<del> </del>	US									
	<del></del>	US		<b>~</b>							
	<del></del>	US									
		υs	·								
		US									
		ÜS									
		US		•		<del></del>					
		US					┪				
FOREIGN PATENT DOCUMENTS											
EXAMINER'S INITIALS	CITE NO.		reign Patent Document intry Codes -Number 4 -Kind Codes (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Figures Appear		Yes	anslation No		
					<del></del>						
	<del>                                     </del>	<u>⊢</u>				<del>                                     </del>					
	<del>                                     </del>	<del>                                     </del>									
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)											
EXAMINER'S INITIALS	CITE NO.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.									
OWA		Hong J. et al, "Etching process of hydrogenated amorphous carbon (a-C:H) thin films in a dual ECR-r.f. nitrogen plasma", vol. 8, no. 2-5, March 1999, pages 572-576, XP004364947									
AWO		Basche B., "Optische Emissionsspektroskopie Zum Analysieren Von Plasma", vol. 98, no. 6, 1 June 1990, pages 272-274, XP000132699									
AWO		Valyi G. et al, "Analysis of chemical processes of plasma etching", vol. 76, no. 3, 13 February 1981, pages 215-219, XP002381595									
AWO Search Report dated June 21, 2008											
EXAMINER					DATE CONSIDERED 12/21/2006						
/Allan Olsen/					12/21/2000						

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.